

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of

Allan Rosencwaig et al.

Application No.: 10/717,316

Filed: November 19, 2003

For: OPTICAL INSPECTION EQUIPMENT
FOR SEMICONDUCTOR WAFERS
WITH PRECLEANING

Confirmation No.: 8272

Group Art Unit: 2877

Examiner: R.M. Punnoose

**SUPPLEMENTAL INFORMATION
DISCLOSURE STATEMENT**353 Sacramento Street, Suite 2200
San Francisco, CA 94111
(415) 772-4900M/S RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450**CERTIFICATE OF MAILING**I hereby certify that this correspondence is being deposited
with the United States Postal Service as First Class Mail in an
envelope, addressed to: Commissioner for Patents, P.O.
Box 1450, Alexandria, VA 22313-1450 on August 2, 2004.
STALLMAN & POLLOCK LLPDated: 08/2 /2004

By:

Georgia K. Stith
Georgia K. Stith

Sir:

Applicant(s) submit(s) herewith patents, publications or other information [attached hereto and listed on the attached Form PTO-1449 (modified)] of which they are aware, which they believe(s) may be material to the examination of this application and in respect of which there may be a duty to disclose in accordance with 37 CFR § 1.56.

This Information Disclosure Statement:

- (a) ☐ accompanies the new patent application submitted herewith. 37 CFR § 1.97(a).
- (b) ☐ is filed within three months after the filing date of the application or within three months after the date of entry of the national stage of a PCT application as set forth in 37 CFR § 1.491.
- (c) ☒ as far as is known to the undersigned, is filed before the mailing date of a first Office Action on the merits, or before a first office action after filing a Request for Continued Examination under §1.114.
- (d) ☐ is filed after the first office action and more than three months after the application's filing date or PCT national stage date of entry filing but, as far as is

known to the undersigned, prior to the mailing date of either a final rejection or a notice of allowance, whichever occurs first, and is accompanied by either the fee (\$180) set forth in 37 CFR § 1.17(p) or a certification as specified in 37 CFR § 1.97(e), as checked below.

- (e) ☐ is filed after the mailing date of either a final rejection or a notice of allowance, whichever occurred first, and the Issue Fee has not been paid, and is accompanied by the fee (\$130) set forth in 37 CFR § 1.17(i)(1) and a certification as specified in 37 CFR § 1.97(e), as checked below. This document is to be considered as a petition requesting consideration of the information disclosure statement.

[If either of boxes (d) or (e) is checked above, the following "certification" under 37 CFR § 1.97(e) may need to be completed.] The undersigned certifies that:

- (f) ☐ Each item of information contained in the information disclosure statement was cited in a communication mailed from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this information disclosure statement.
- (g) ☐ No item of information contained in this information disclosure statement was cited in a communication mailed from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned after making reasonable inquiry, was known to any individual designated in 37 CFR § 1.56(c) more than three months prior to the filing of this information disclosure statement.

A list of the patent(s) or publication(s) is set forth on the attached Form PTO-1449 (Modified).

A copy of the items on PTO-1449 (Modified) is supplied herewith, except as noted below.

Those patent(s) or publication(s) which are marked with an asterisk (*) in the attached form PTO-1449 (Modified) are not supplied because they are (a) either U.S. Patents and this an application filed after June 30, 2003, or (b) were previously cited by or submitted to the Office in a prior application no. _____, filed _____, and relied upon in this application for an earlier filing date under 35 U.S.C. § 120.

A concise explanation of relevance of the items listed on form PTO-1449 (Modified) is:

- (h) ☐ not given

- (i) ☐ given for each listed item
- (j) ☒ given for only non-English language listed item(s) [Required]
- (k) ☐ is in the form of an English language copy of a Search Report from a foreign patent office, issued in a counterpart application, which refers to the relevant portions of the references [copy attached].

With respect to Japanese Patent No. 10-137704, the following information is derived from a DIALOG search:

“Semiconductor cleaning method using microwave excitation--involves reducing surface tension of cleaning liquid and cleaning substrate, by microwave irradiation.

The method involves immersing a silicon substrate (6) in a cleaning liquid (4) contained in a washing tank (3) made of quartz. A microwave with frequency range of 0.4-25GHz is irradiated on the cleaning liquid. By microwave irradiation, the surface tension of cleaning liquid is reduced and the substrate is cleaned.

ADVANTAGE - Removes contamination adhering to inner portions of holes, effectively. Offers high precision of cleaning. Produces high quality substrate.”

The Examiner is reminded that a "concise explanation of the relevance" of the submitted items "may be nothing more than identification of the particular figure or paragraph of the patent or publication which has some relation to the claimed invention," MPEP § 609.

While the information and references disclosed in this Information Disclosure Statement may be "material" pursuant to 37 CFR § 1.56, it is not intended to constitute an admission that any patent, publication or other information referred to therein is "prior art" for this invention unless specifically designated as such.

In accordance with 37 CFR § 1.97(g), the filing of this Information Disclosure Statement shall not be construed to mean that a search has been made or that no other material information as defined in 37 CFR § 1.56(a) exists. It is submitted that the Information Disclosure Statement is in compliance with 37 CFR § 1.98 and MPEP § 609 and the Examiner is respectfully requested to consider the listed references.

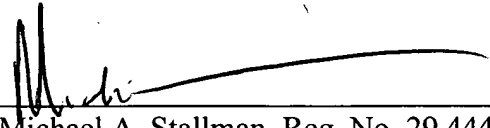
- ☒ The Commissioner is hereby authorized to charge our Deposit Account No. 50-1703, under Order No. TWI-8520, for any fees required in connection with the filing of this

Information Disclosure Statement. **A duplicate copy of this Notice is enclosed for this purpose.** In particular, in the event that an Office Action has crossed in the mail with this Information Disclosure Statement, the Commissioner is authorized to charge the above-named deposit account for any fees required pursuant to CFR §§ 1.17(p) or 1.17(i)(1).

Respectfully submitted,

STALLMAN & POLLOCK LLP

Dated: August 2, 2004

By: 
Michael A. Stallman Reg. No. 29,444

Attorneys for Applicant(s)



INFORMATION DISCLOSURE CITATION
(Use several sheets if necessary)

Docket Number (Optional)

TWI-8520

Application Number

10/717,316

Applicant(s)

Allan Rosencwaig et al.

Filing Date

November 19, 2003

Group Art Unit

2877

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
	BA	WO 95/00681	01/05/1995	PCT	C23G	1/00		
	BB	10-137704	11/08/1996	Japan (see Dialog Abstract in IDS text)	B08B	3/12		
	BC	WO 98/05066	02/05/1998	PCT	H01L	21/66		
	BD	WO 99/35677	07/15/1999	PCT	H01L	21/306		
	BE	4-357836	12/10/1999	Japan	H01L	21/304	Translation	

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

	BF	K. Imen et al., "Laser-assisted micron scale particle removal," <i>App. Phys. Lett.</i> , Vol. 58, No. 2, 14 January 1991, pp. 203-205.

Examiner

Date Considered

Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.